SUPPORTING INFORMATION

for

"Rapid Processing of Wafer-scale Anti-Reflecting 3D Hierarchical Structures on Silicon and its Templation"

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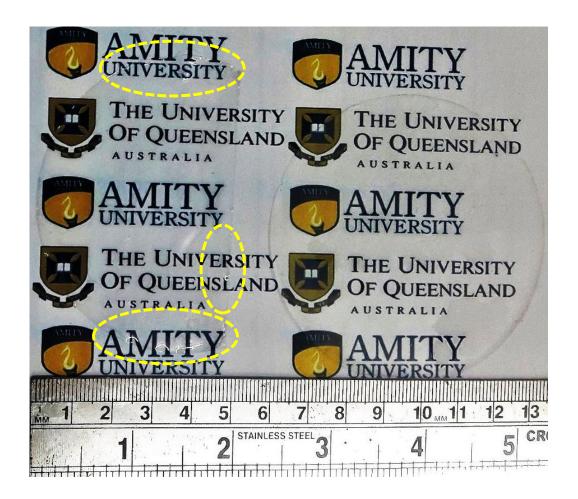
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Figure S1: The Digital image comparisition of the plain PDMS (left) and the partterned PDMS (right).